



Materials Opportunities on Layered Manufacturing Technology 2 - (MOLMT-2)

Micro-fabrication Employing UV Microstereolithography

Professor Chris Chatwin, Dr R.C.D.Young,
Dr D. Budgett, Phil Birch - University of Sussex, UK

Organised by Professor Brian Derby - Manchester Materials Science
Centre, UMIST; June 3rd - 6th - 2001, Weston Conference Centre,
UMIST, Manchester, UK



Fabrication of high aspect ratio 3D micro-components

- Develop a new microstereolithography technique that operates in the UV and Visible part of the spectrum
- Manufacture micro-components which are complex in shape and have micron resolution

Existing Technologies for MicroFabrication

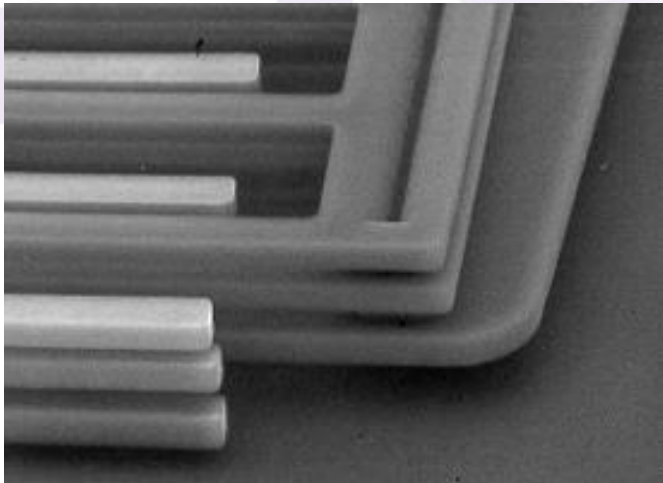
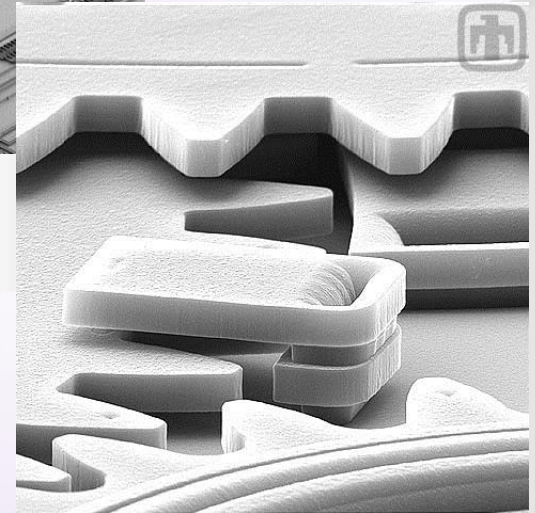
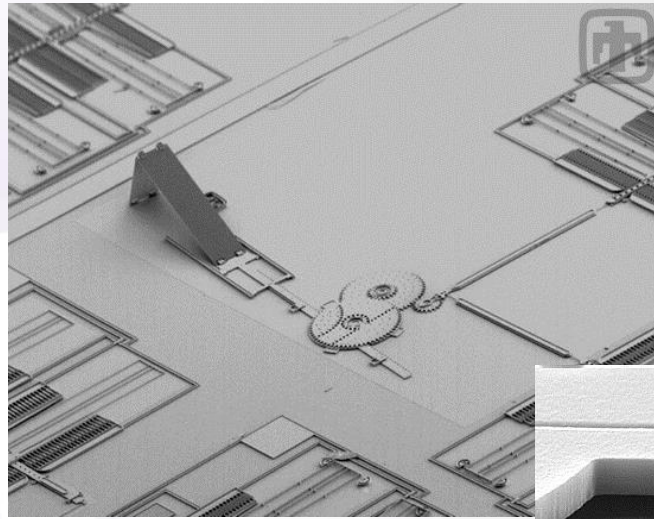
- **Lithography**

Components constructed by superimposing a limited number of thin film layers or by using deep UV lithography.

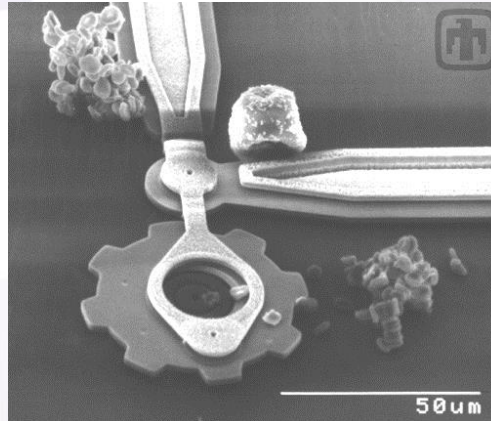
Permits only limited complexity in the third dimension.



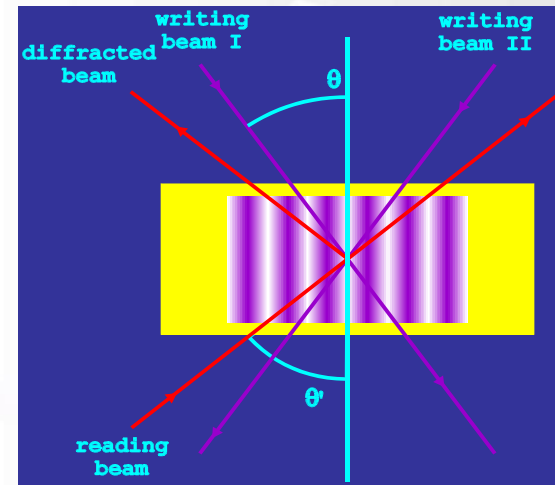
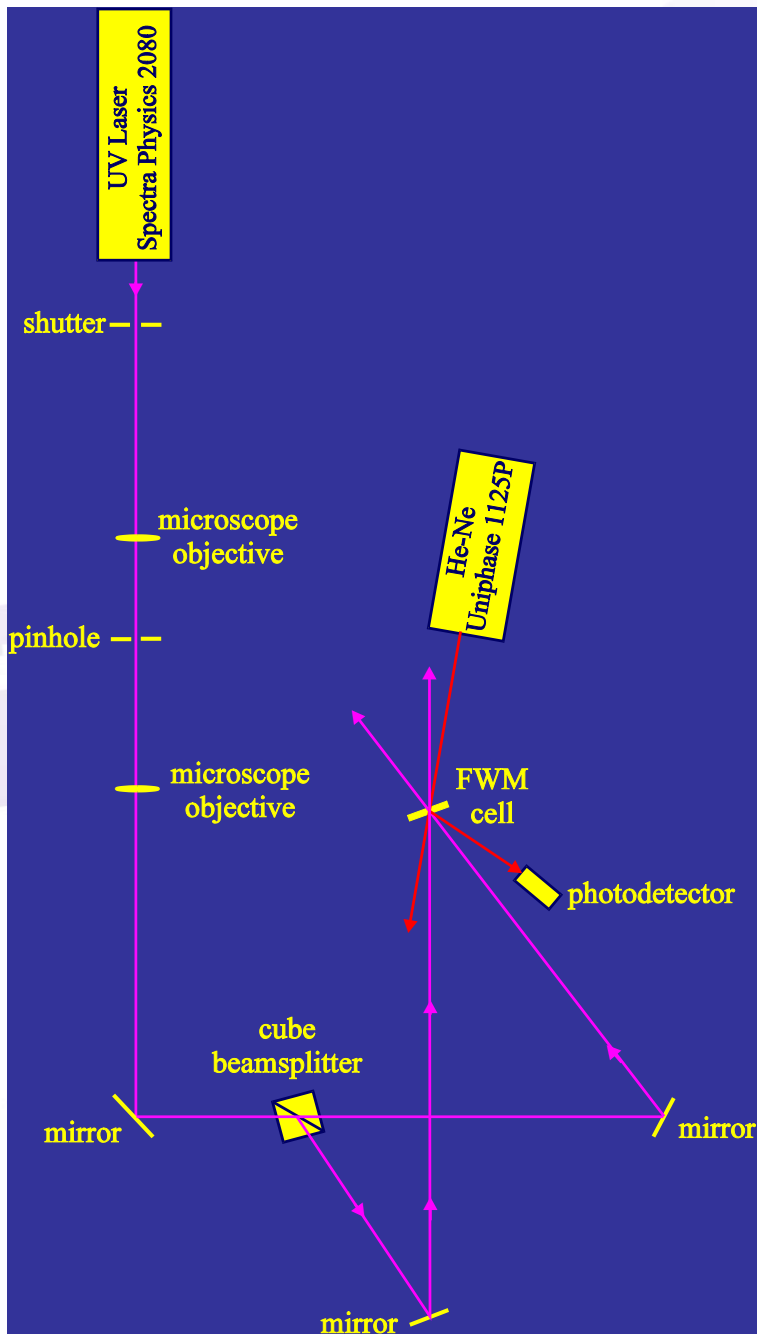
Meshing gears on a moveable platform.



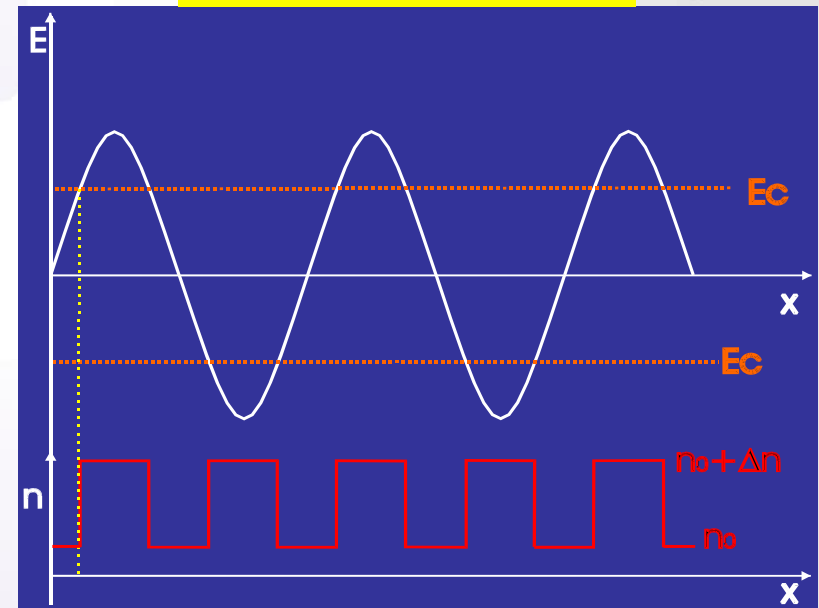
A laminated comb actuator results in nearly five times the electrostatic force of a single level actuator.



Grain of pollen and red blood cells



$$I(x) = I_0 \cdot (1 + m \cos(kx))$$



Cibatool™ SL 5180 and Somos™ 6100

Experimental Conditions:

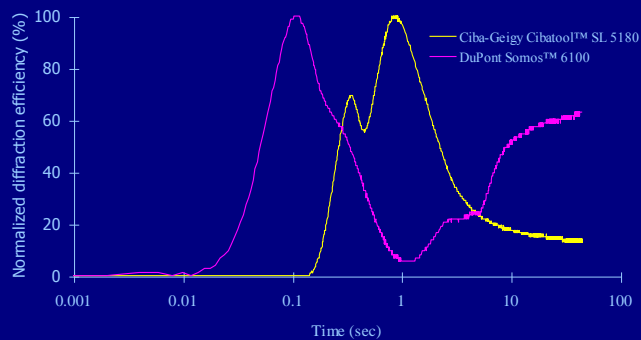
Sample Thickness = 100 μm

Temperature 19 °C

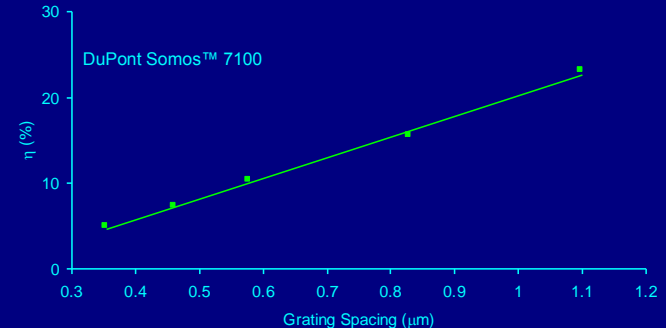
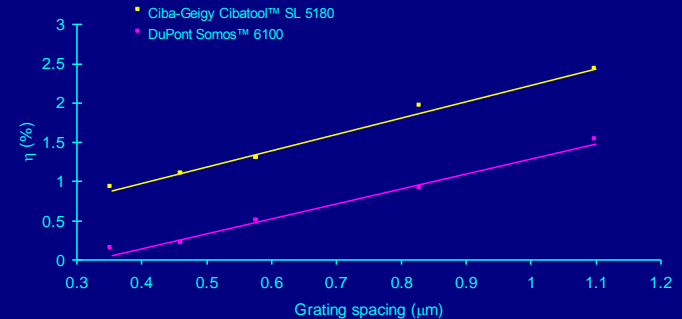
Relative Humidity 50-60 %

Cibatool™ SL 5180: non-viscous, good quality samples

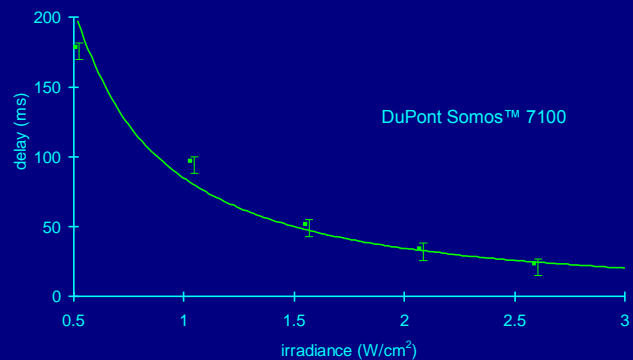
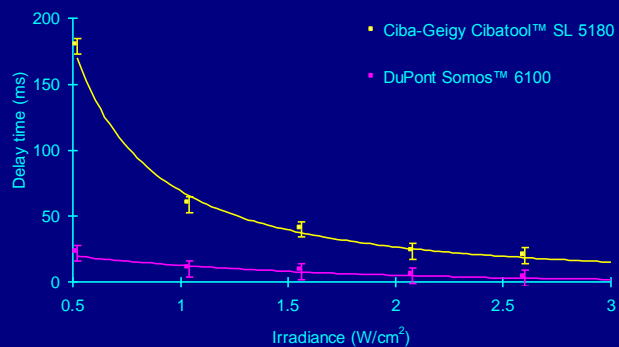
Somos™ 6100: viscous, suffers from 'bubble trapping' that causes scattering



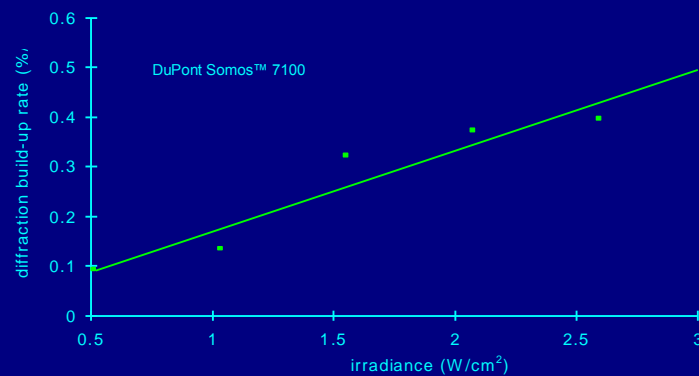
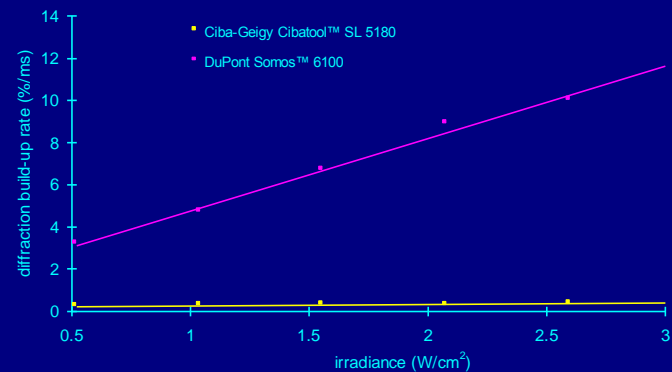
Diffraction efficiency



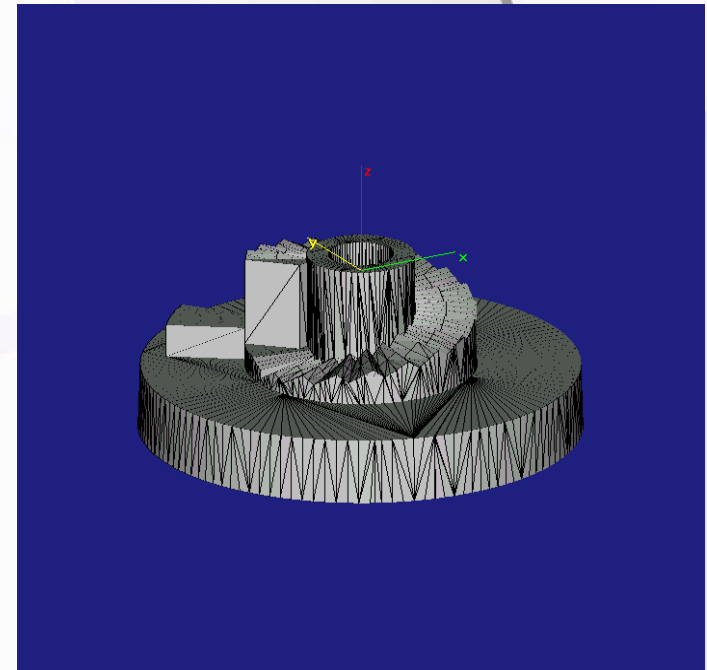
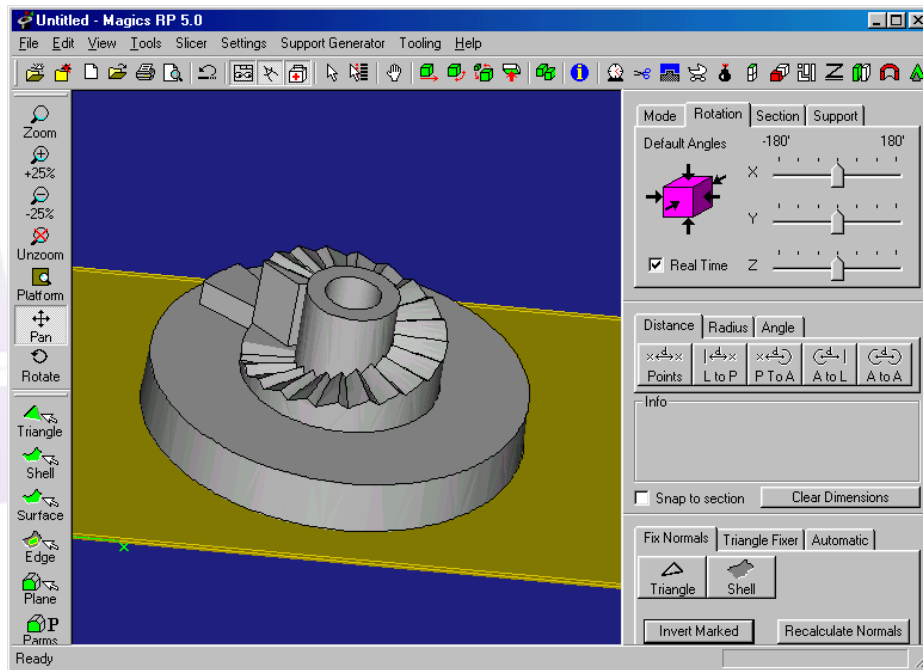
Delay



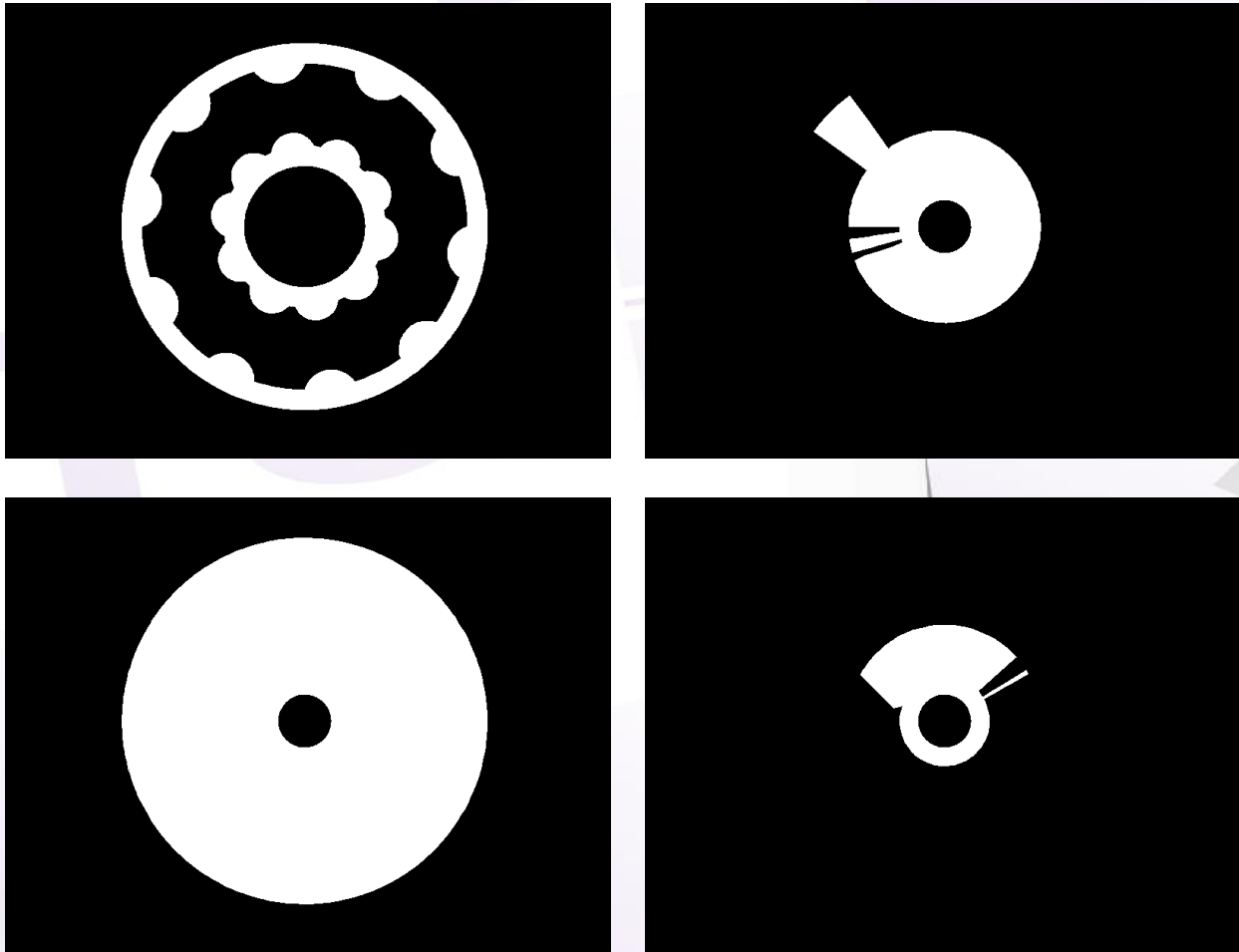
Rate



STL Interface

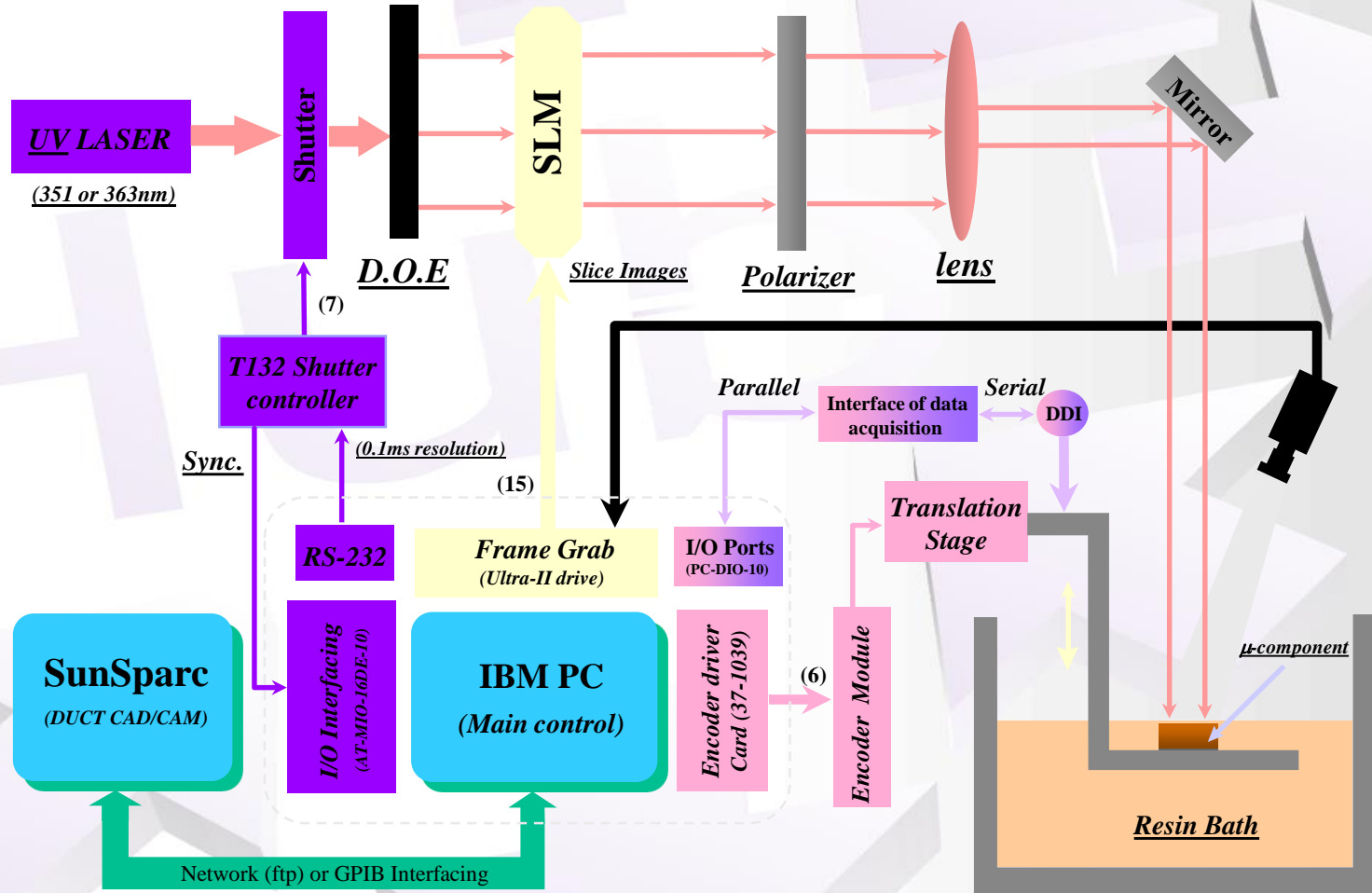


Slices from STL Model

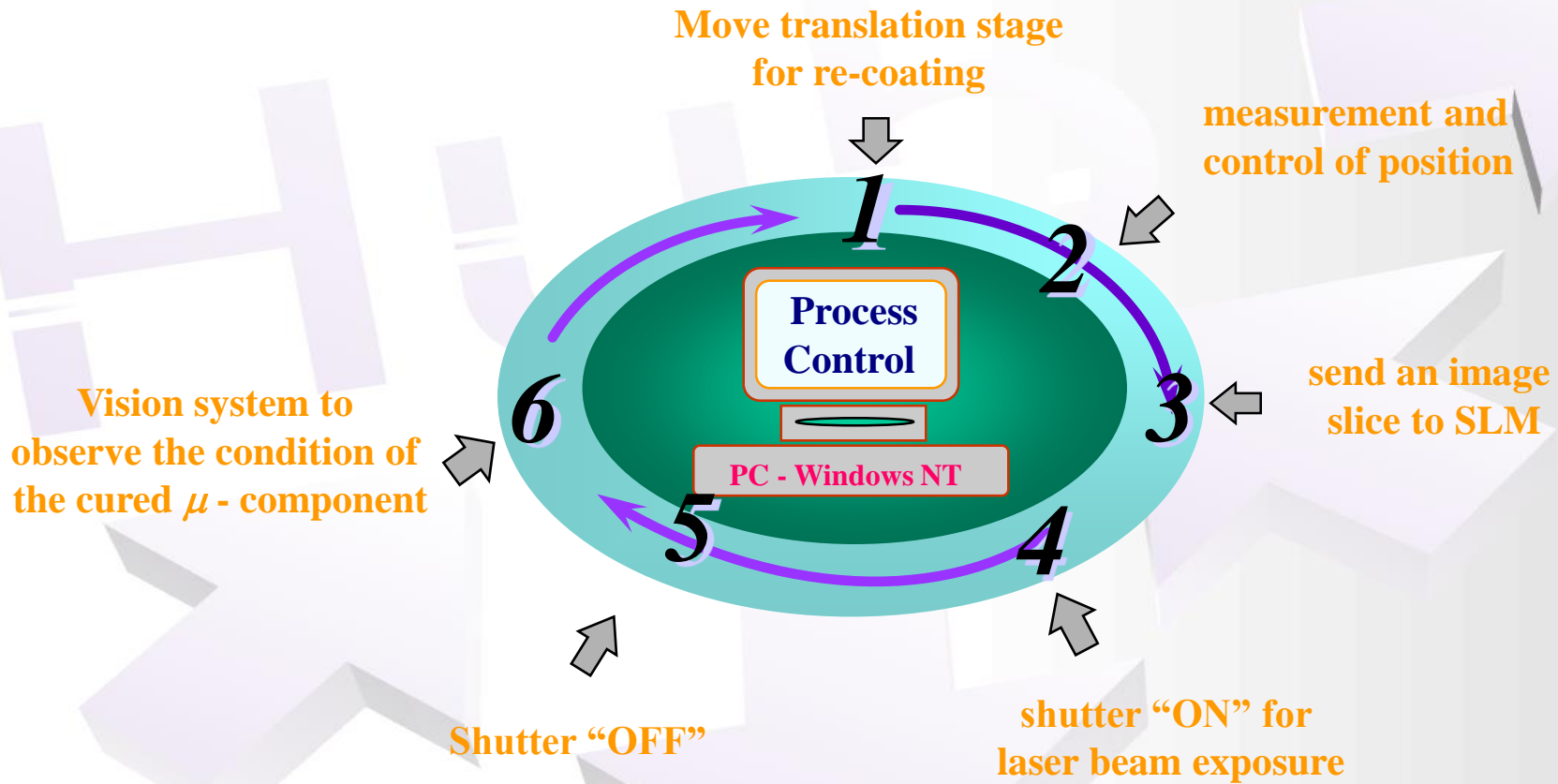


Experimental Set-up

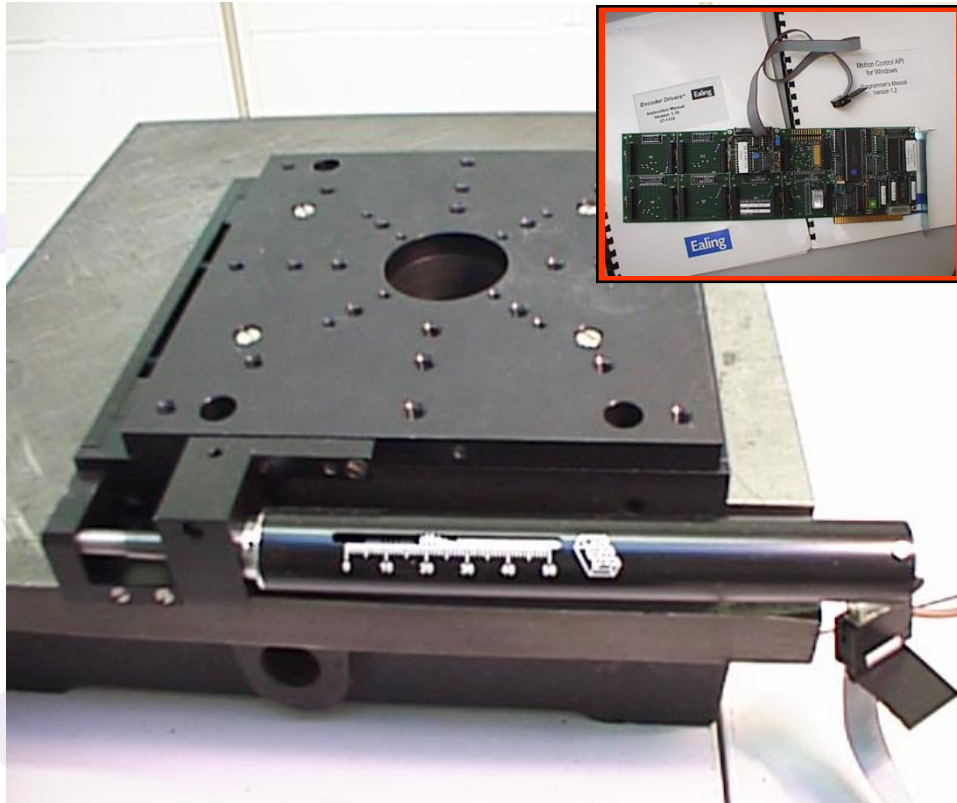
Microstereolithography System Diagram



Basic Control Process



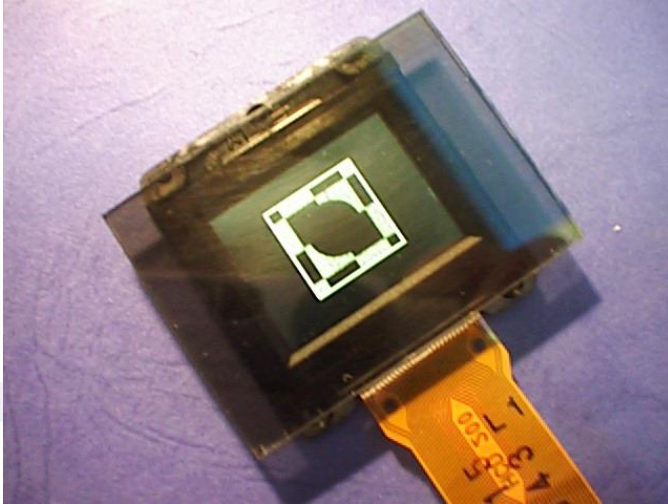
Translation Stage



Features

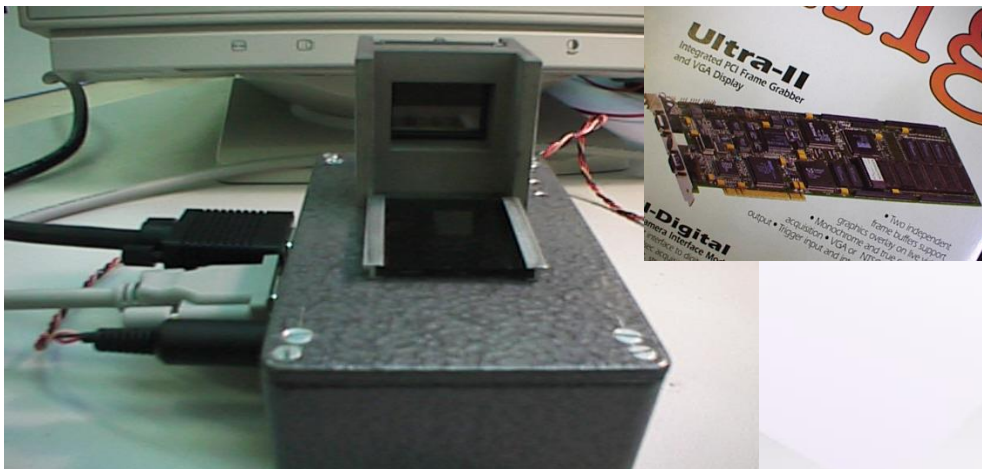
- 20nm resolution
- 0.1 μ m accuracy
- 50mm travel range
- DC servo motor
- PID feedback control with encoder actuator
- Gearhead ratio of 485:1

Spatial Light Modulator (SLM)

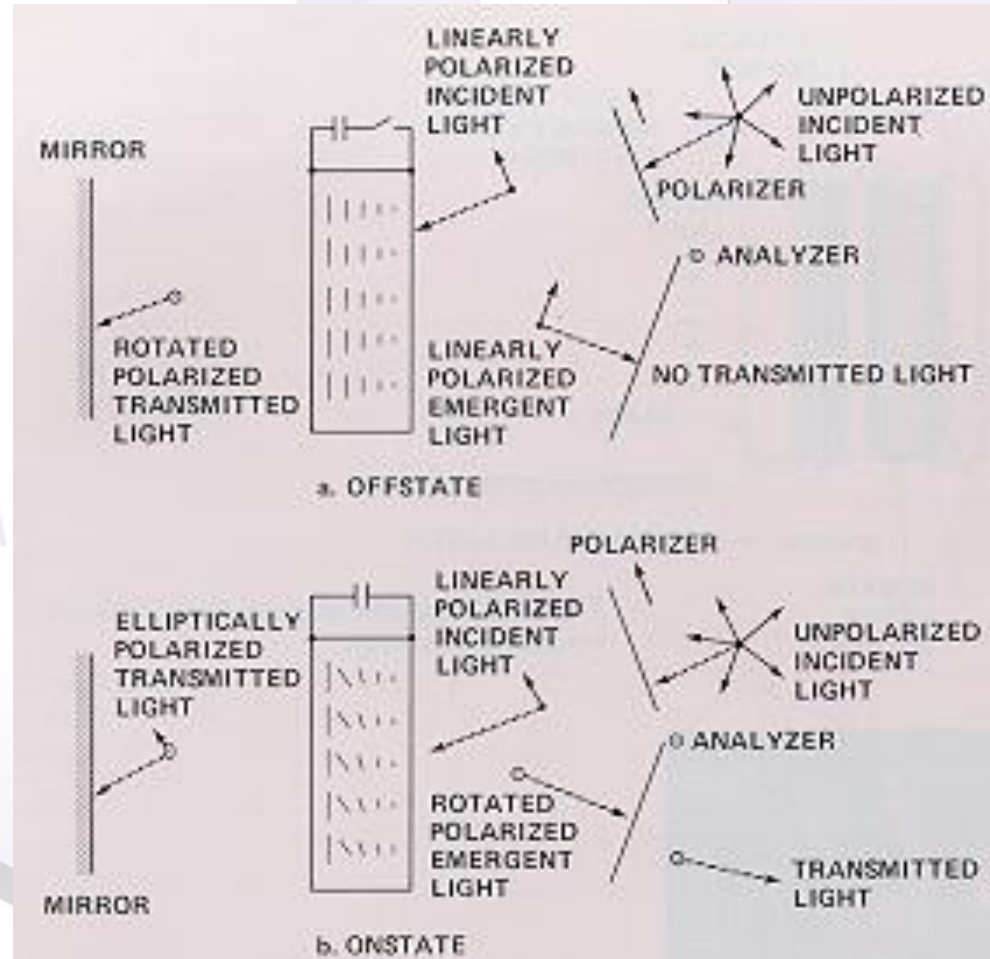


SVGA SLM 800x600 pixels

- Features
- VGA and SVGA
- Ultra-II PCI Frame Grab with video and VGA frame buffers (2Mb each)
- CCIR/PAL camera
- Overlay display



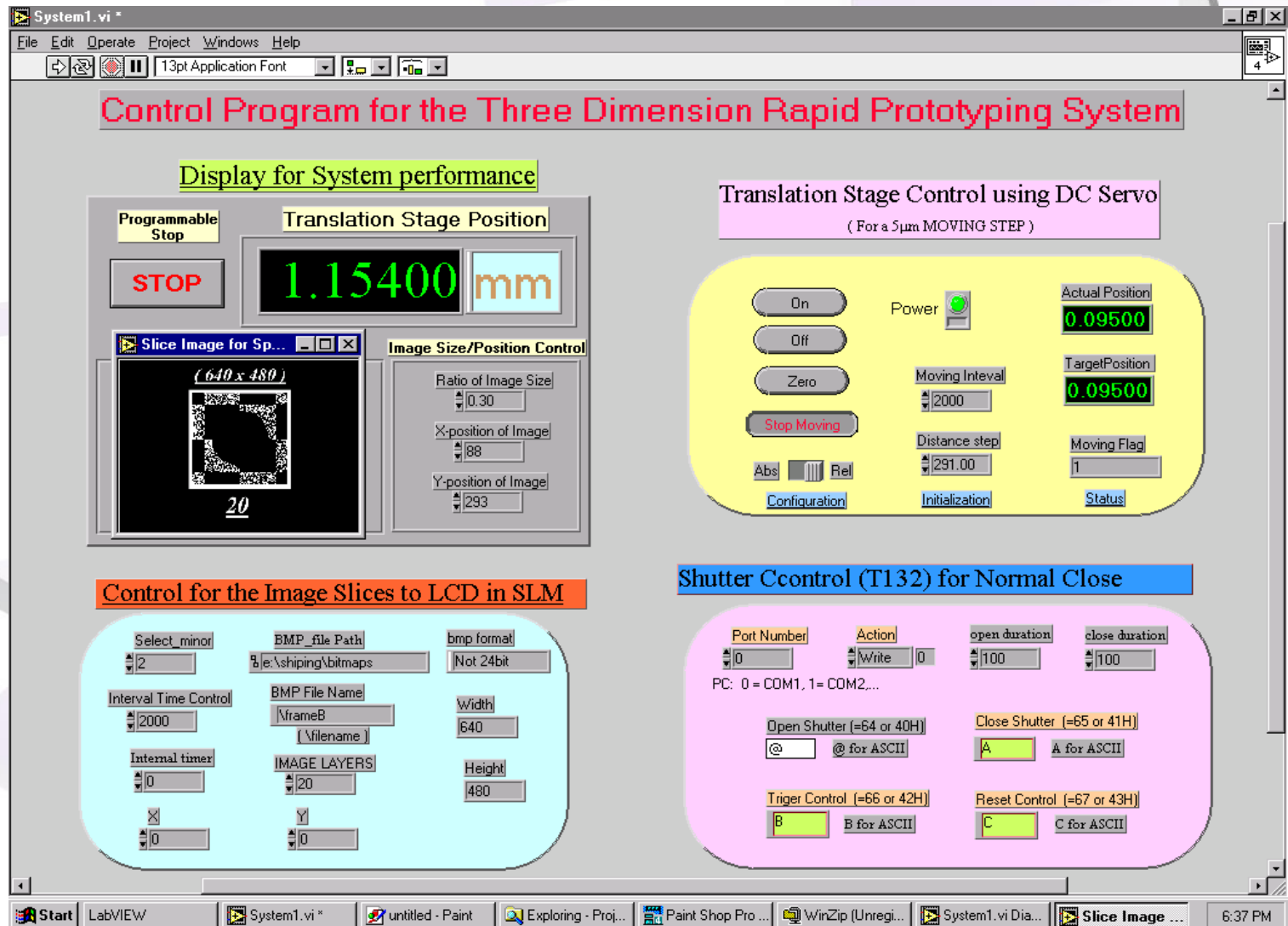
Twisted Nematic Liquid Crystal





Reduction Lens and Photo-polymer Bath

Main Programme Control Panel



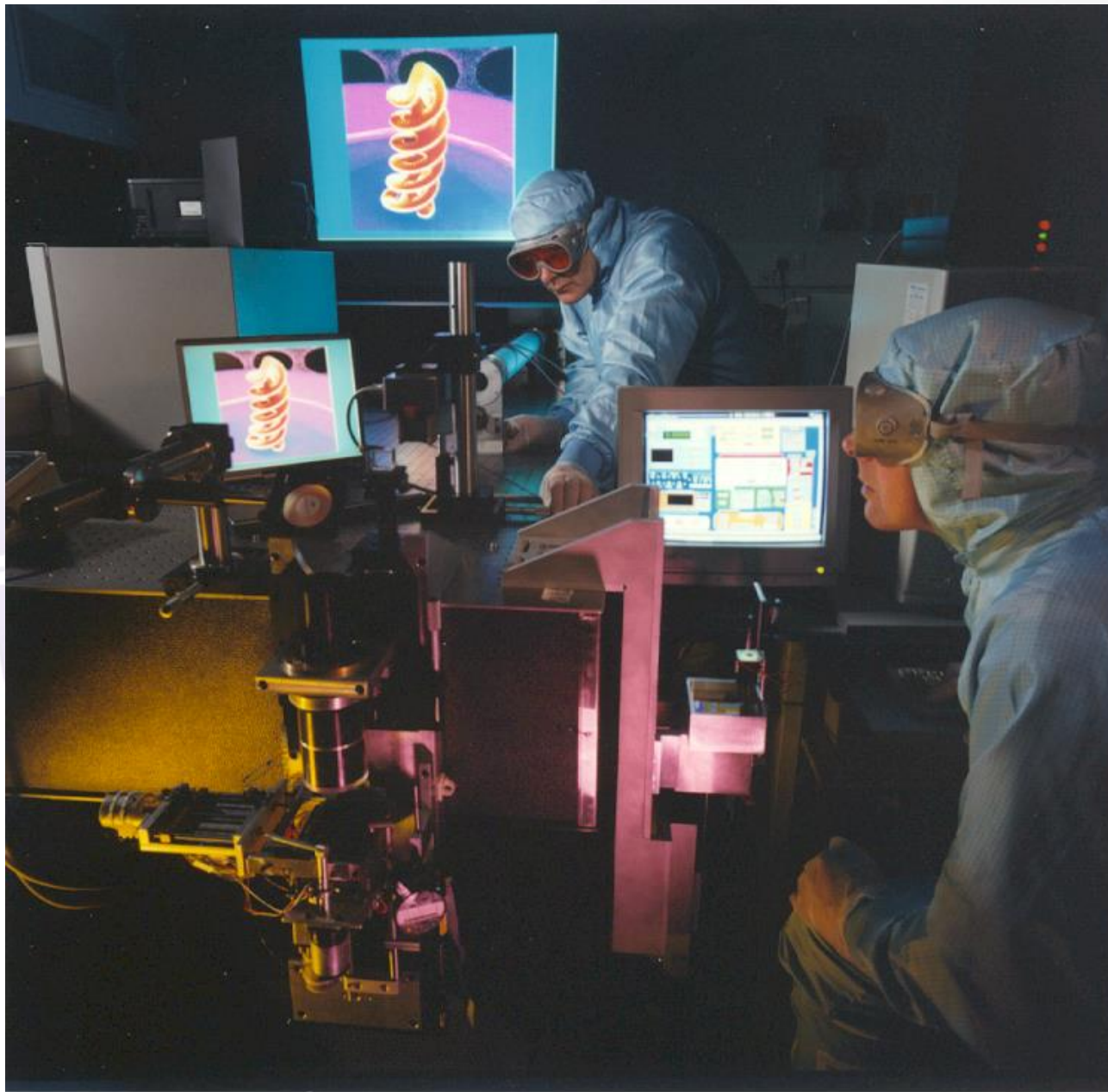


Interface Control

Micro-SLA System

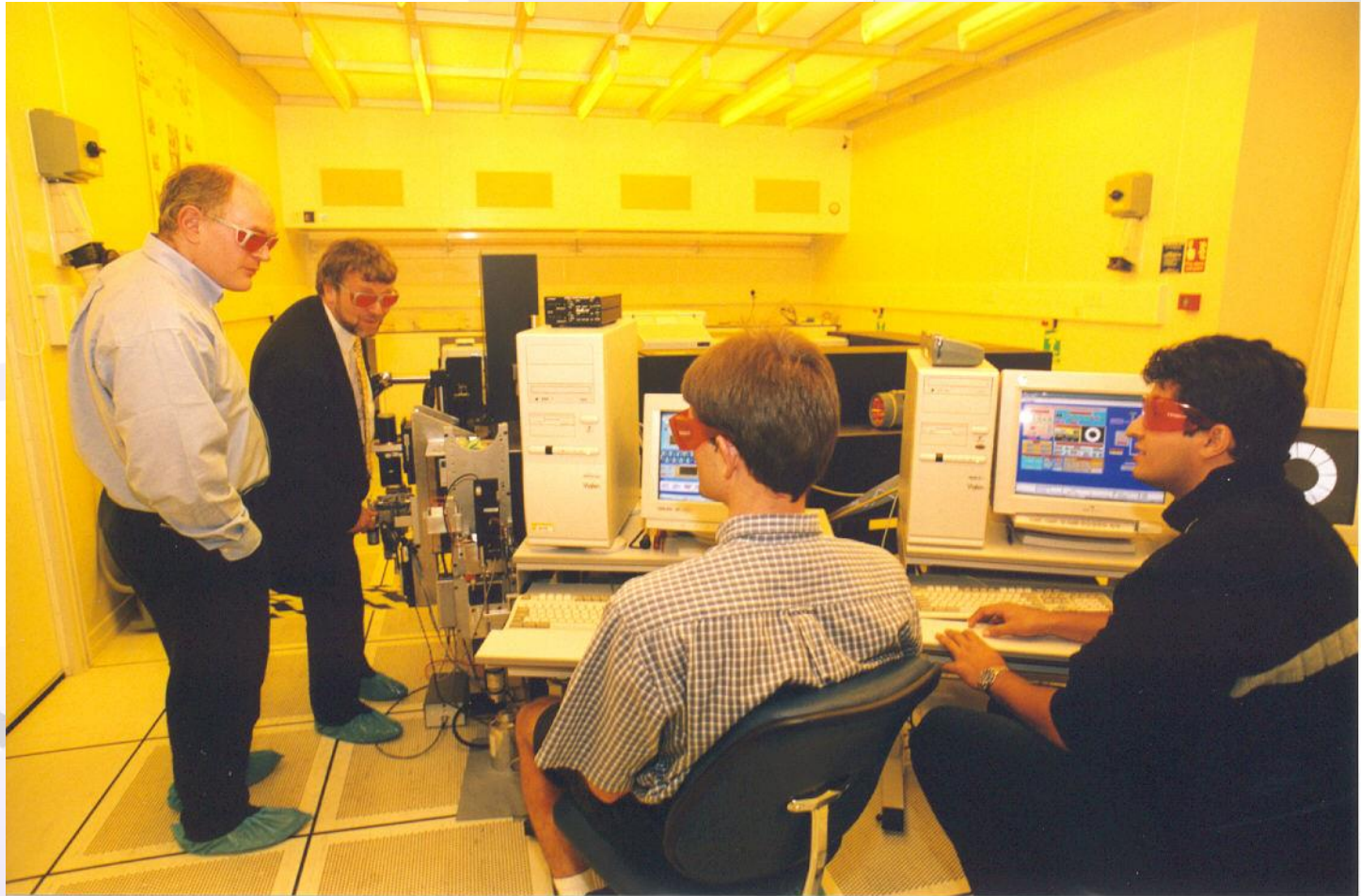
Lithographic Lens

Resin Bath

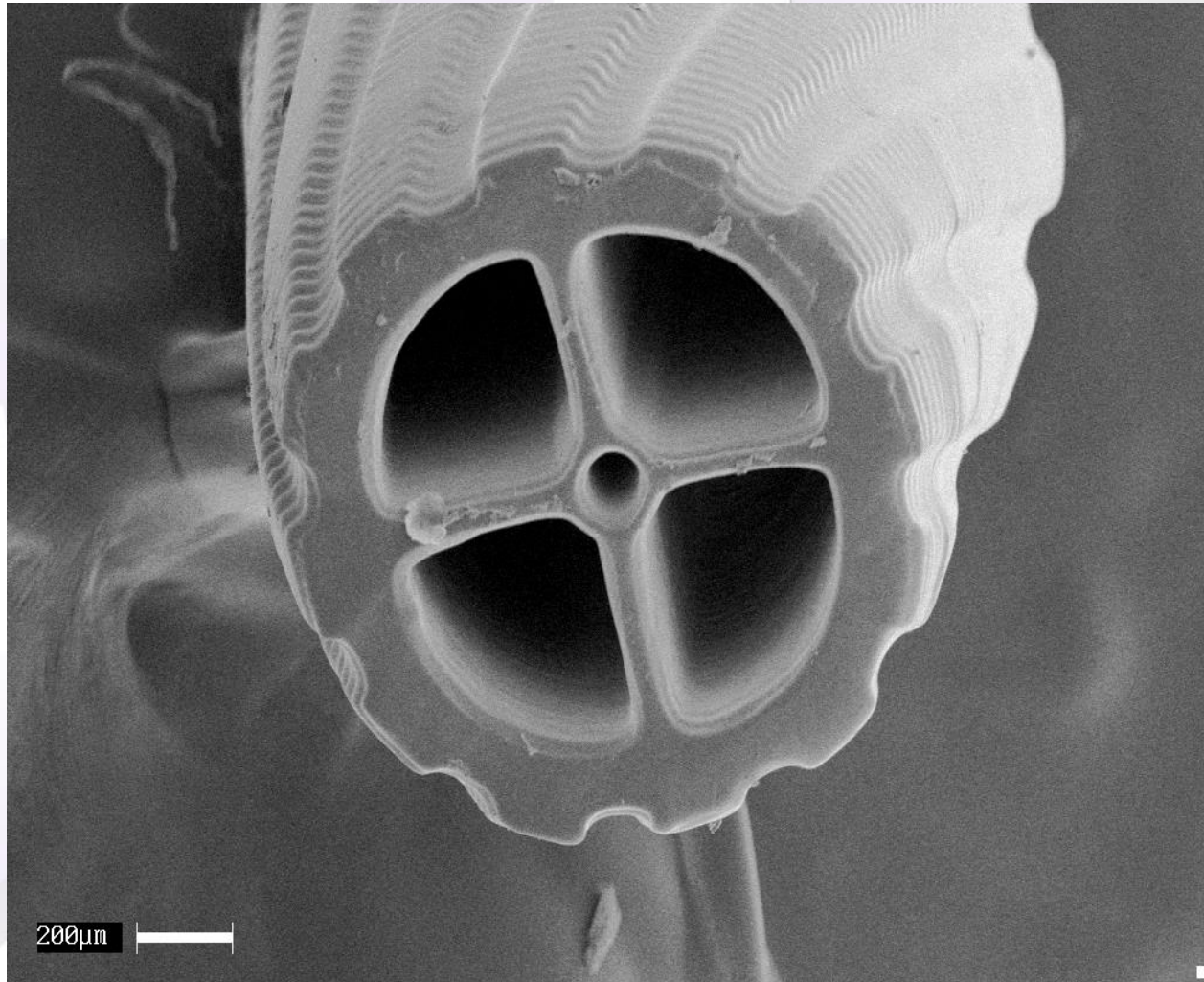


Micro-SLA System

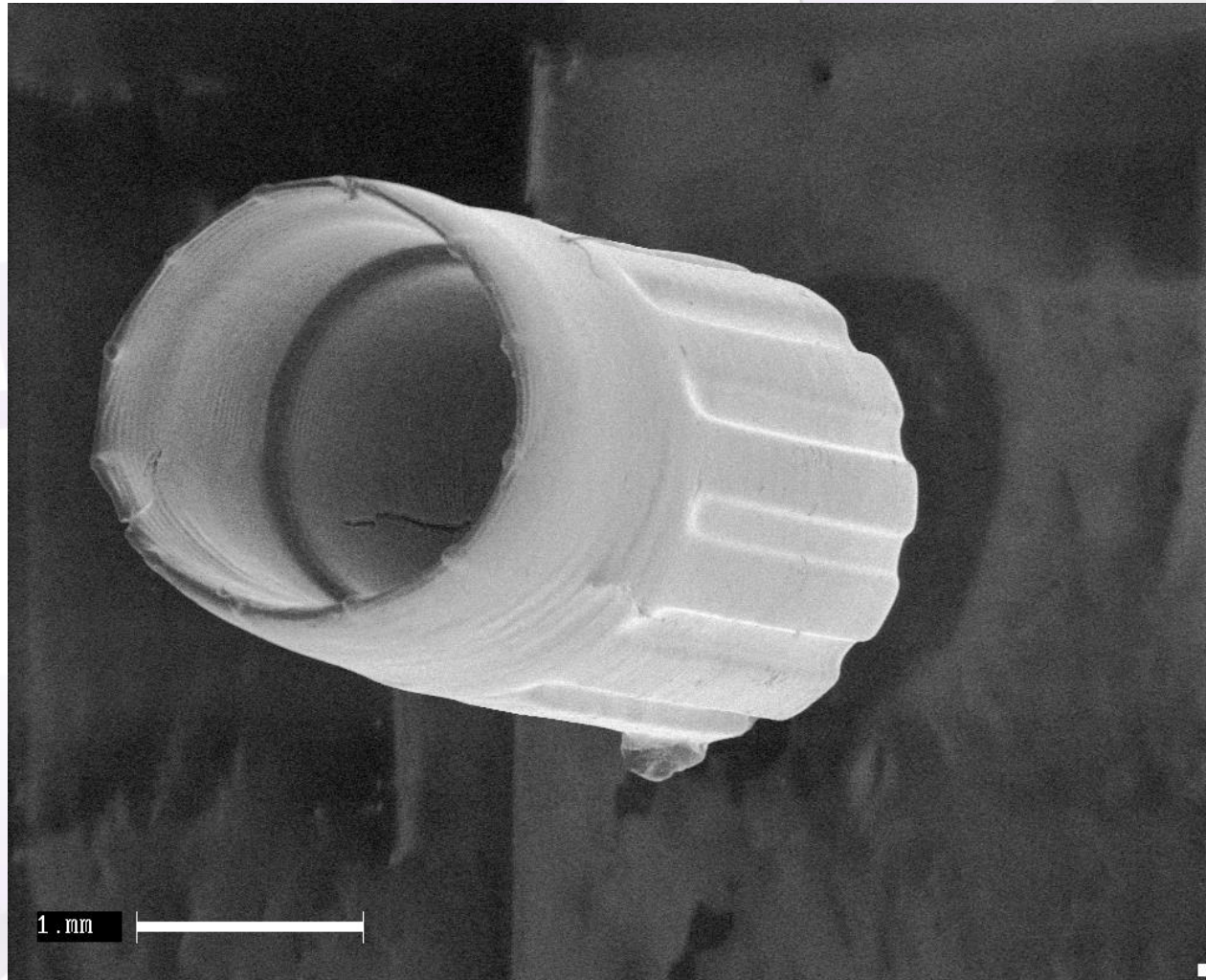
MicroSLA System



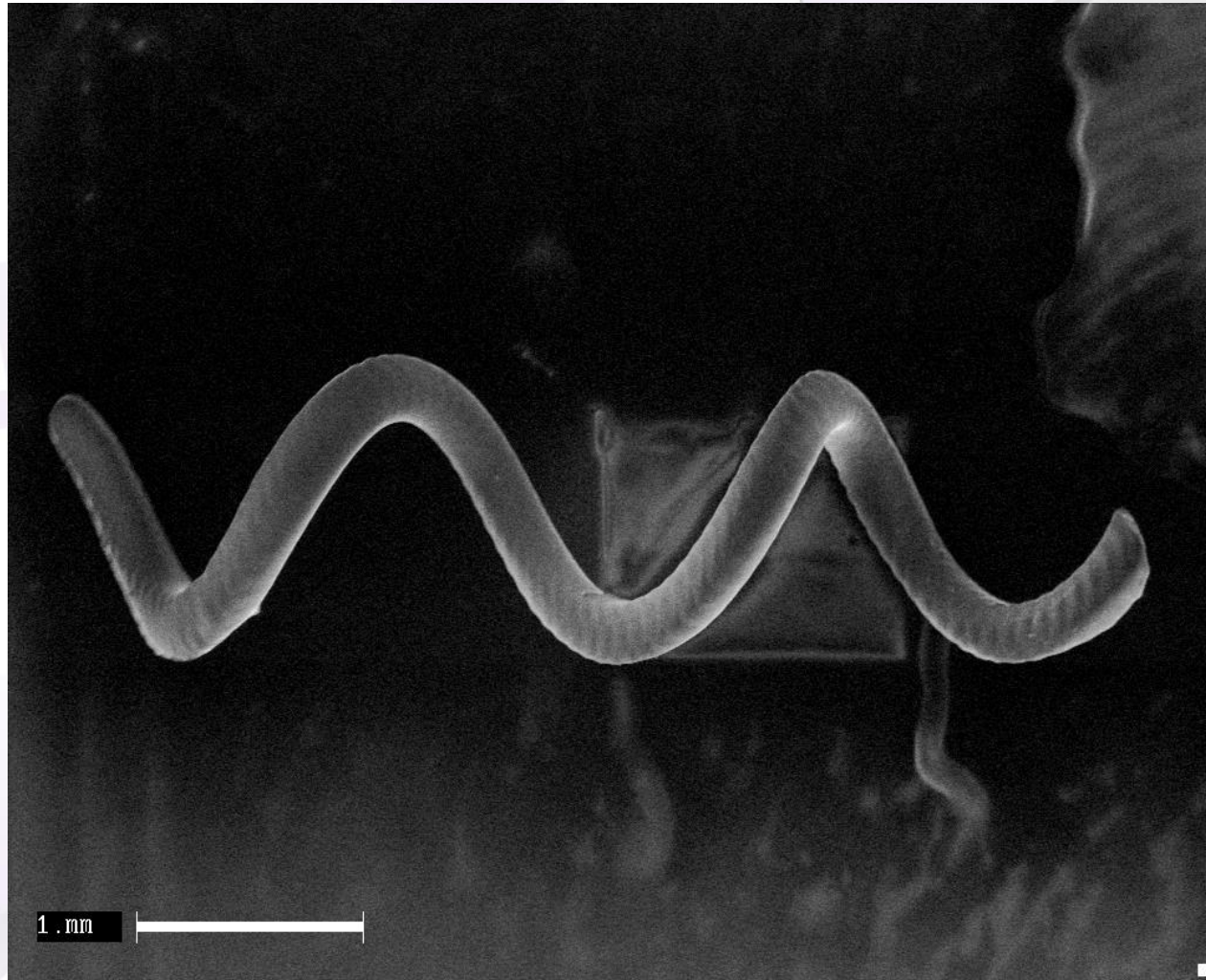
A micro-gear (50 micron layers)



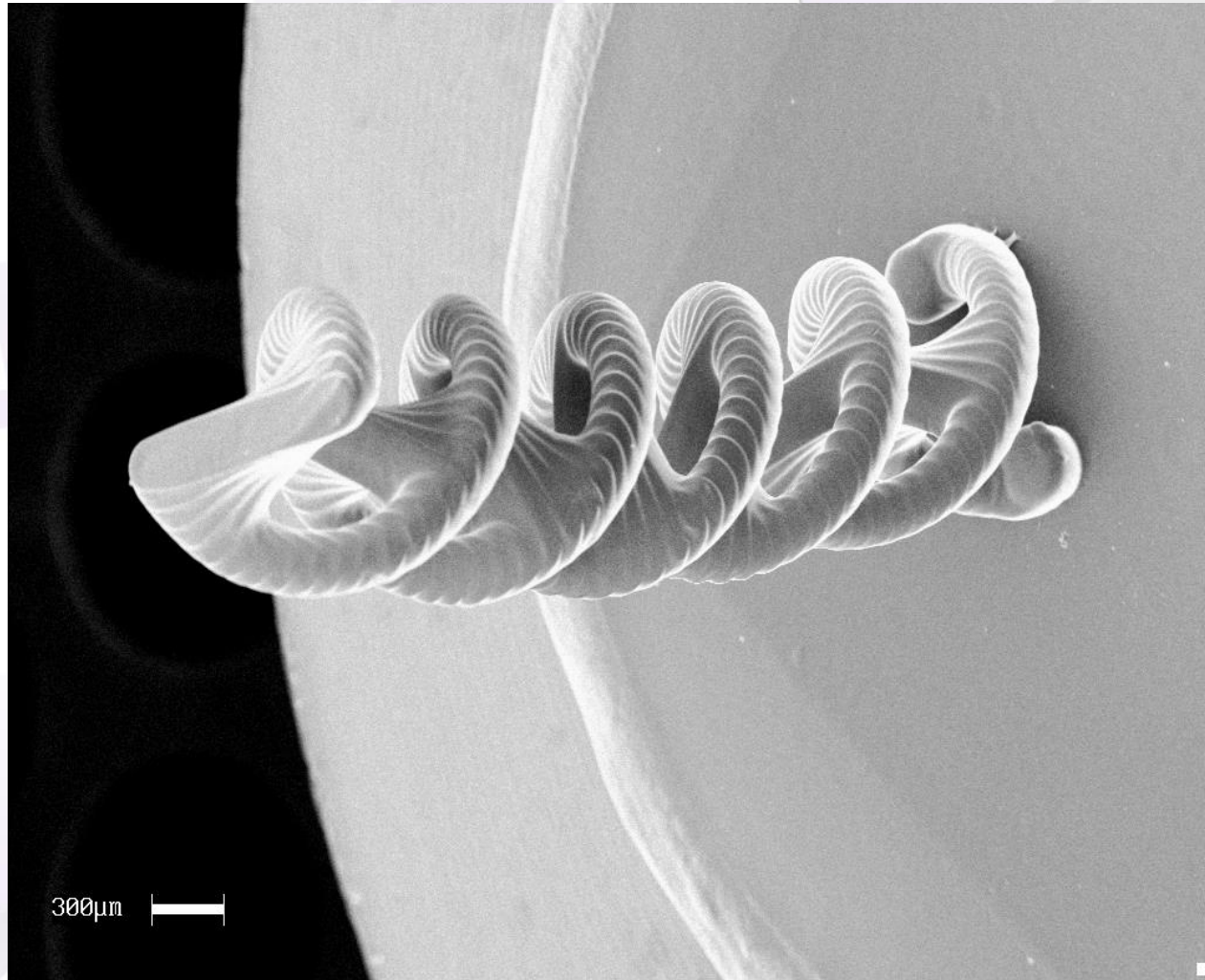
A case for a micro-motor (50 micron layers)



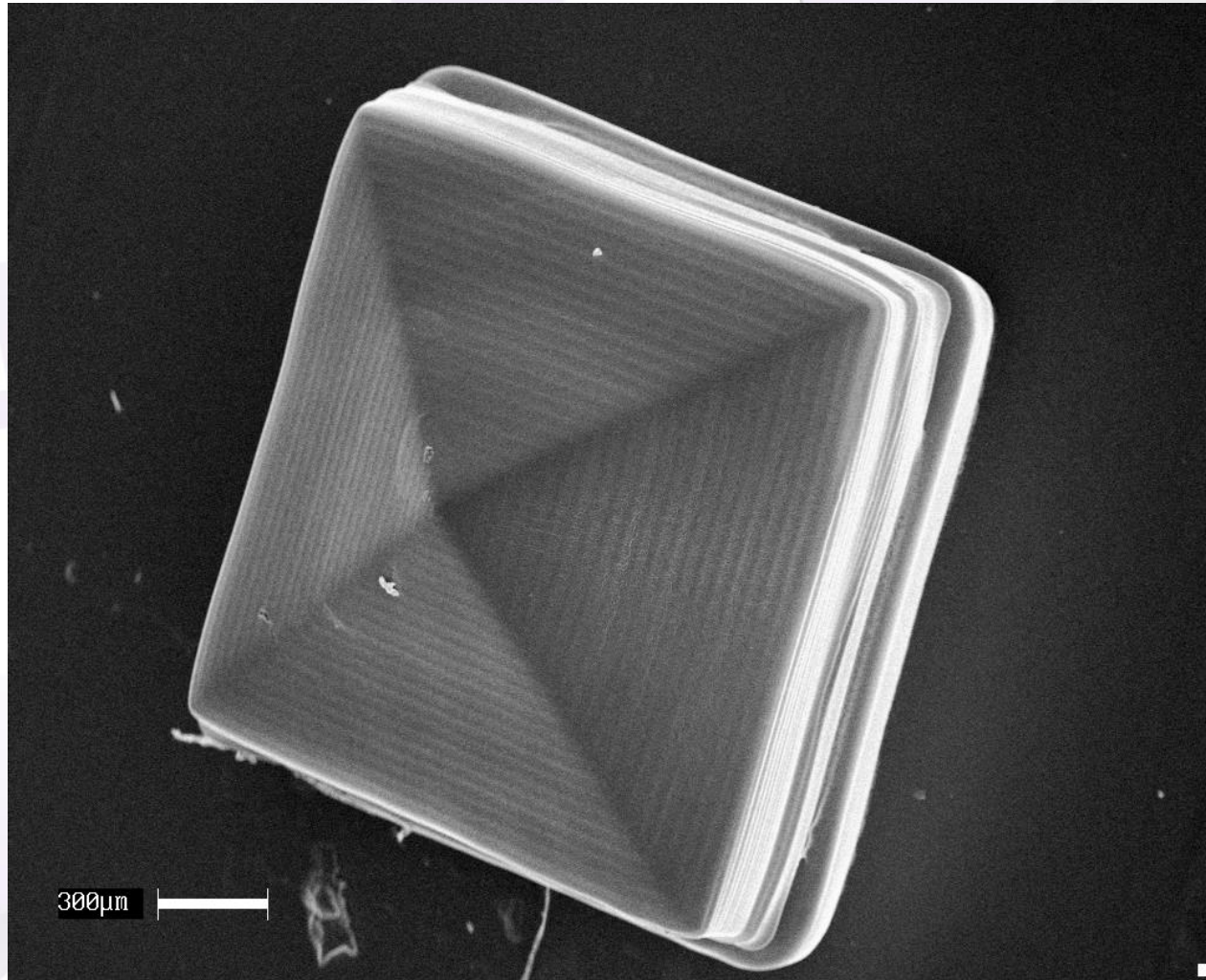
A helix (50 micron layers)



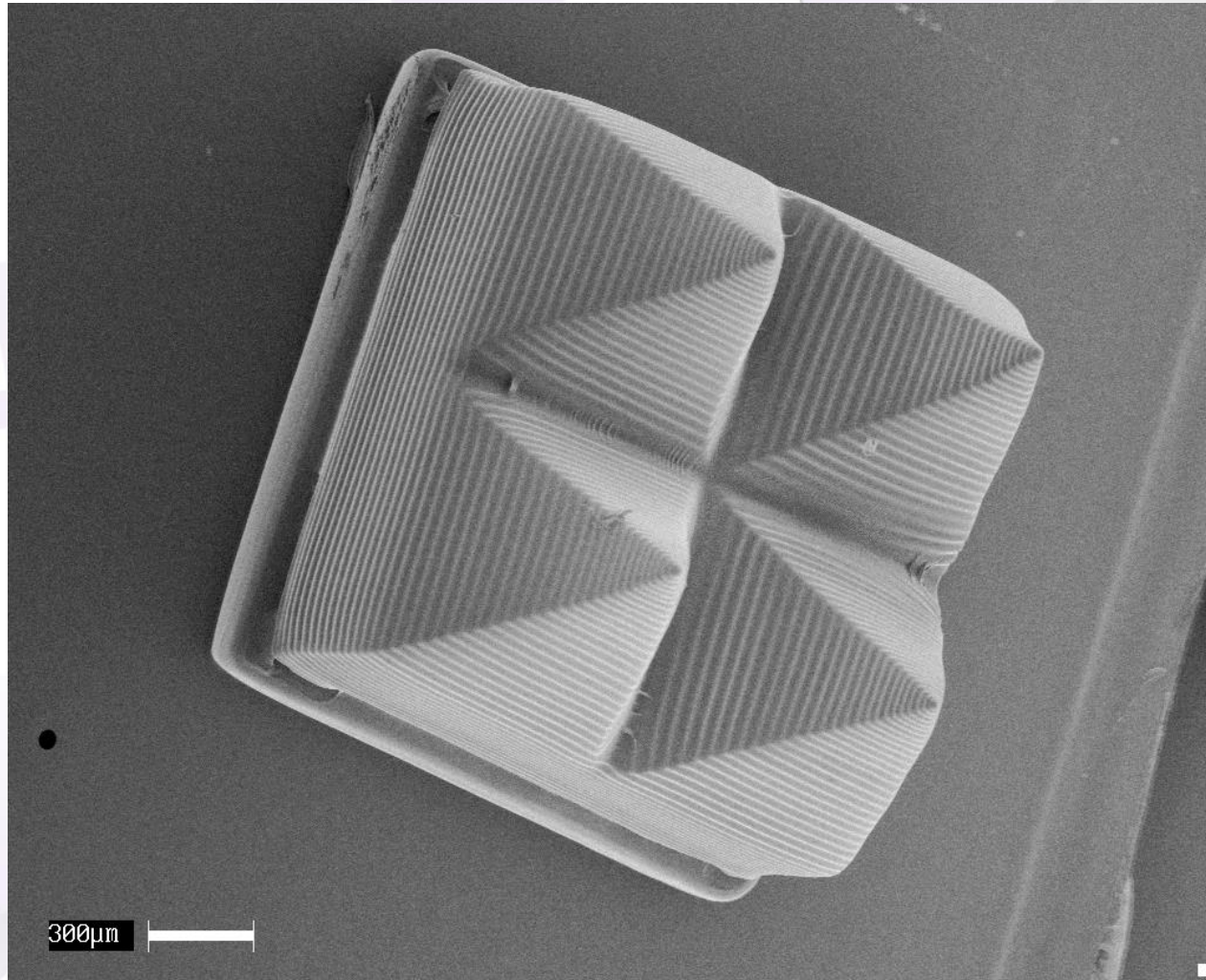
A double helix (50 micron layers)



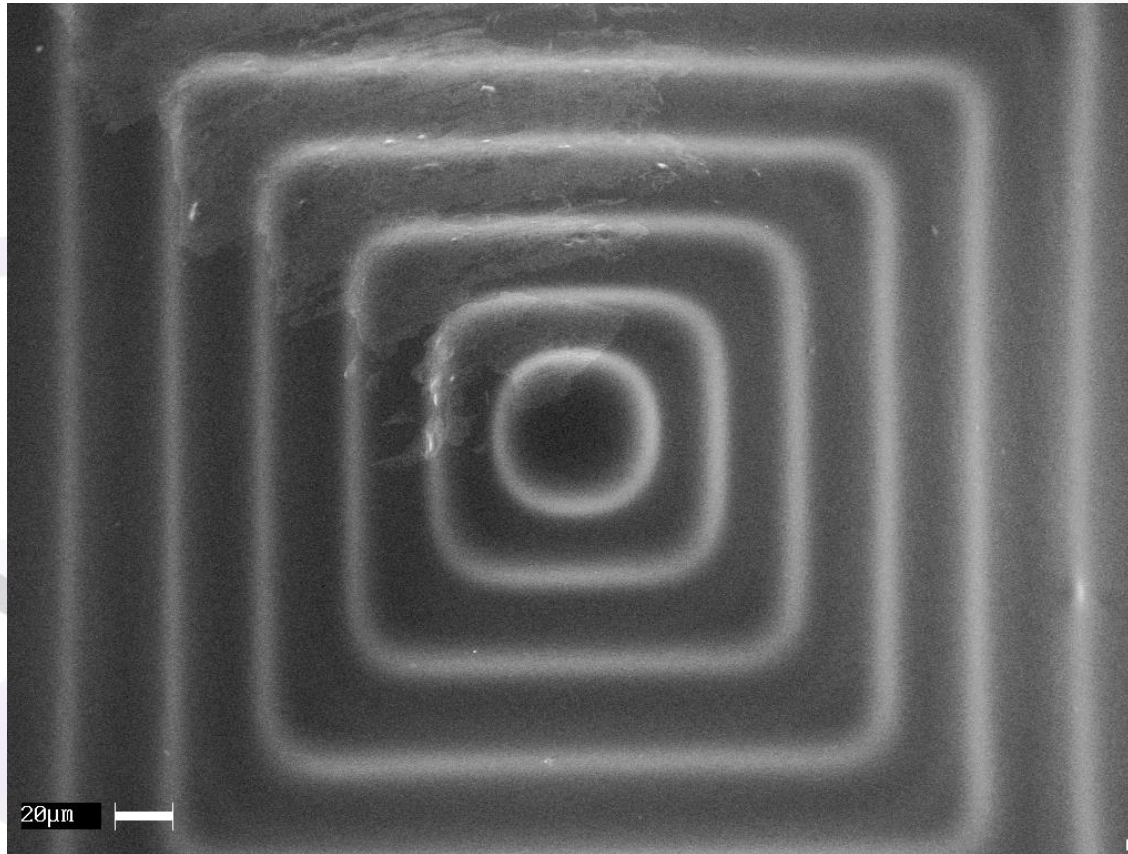
A micro-pyramid (35 micron layers)



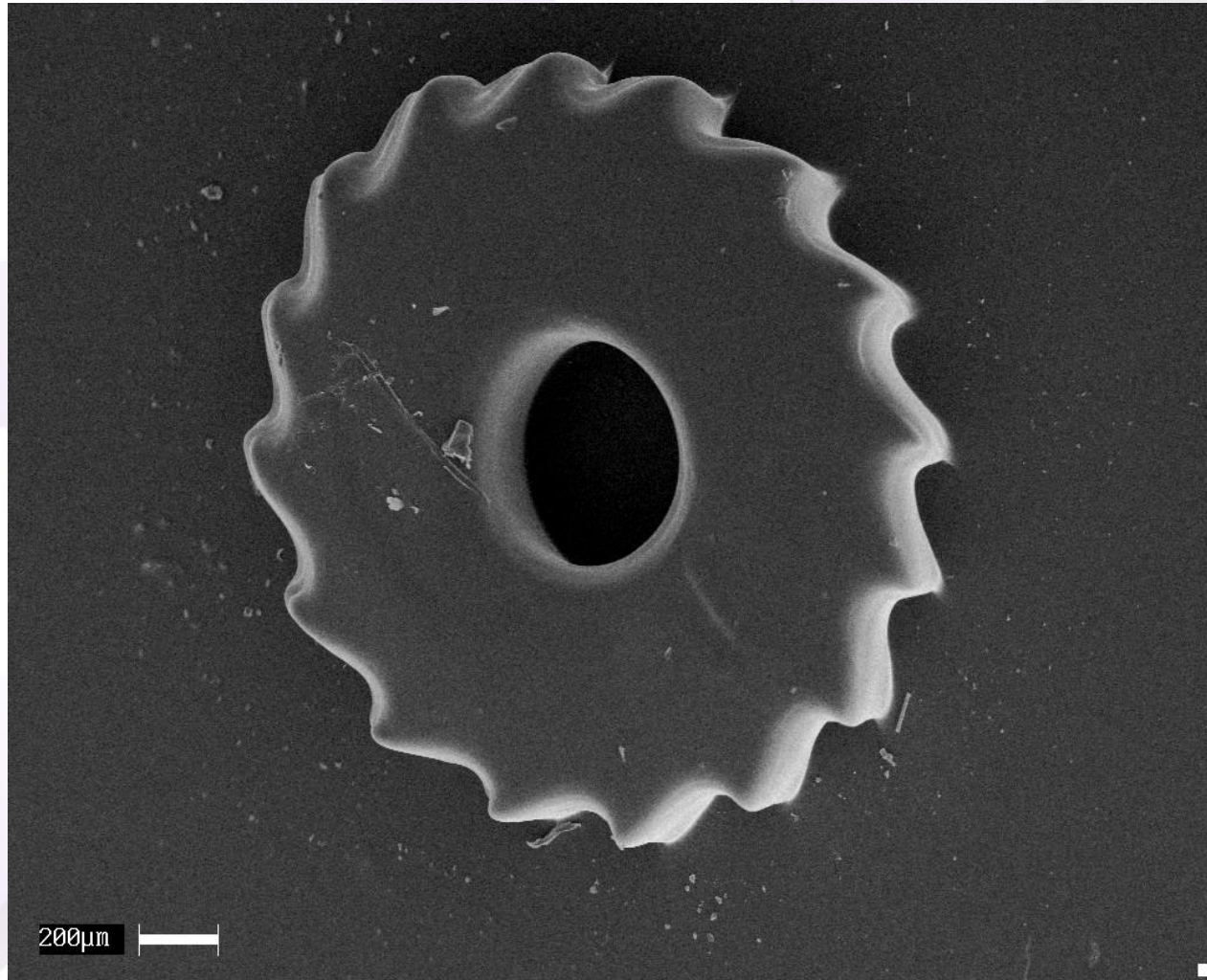
Micro-pyramid (50 micron layers)



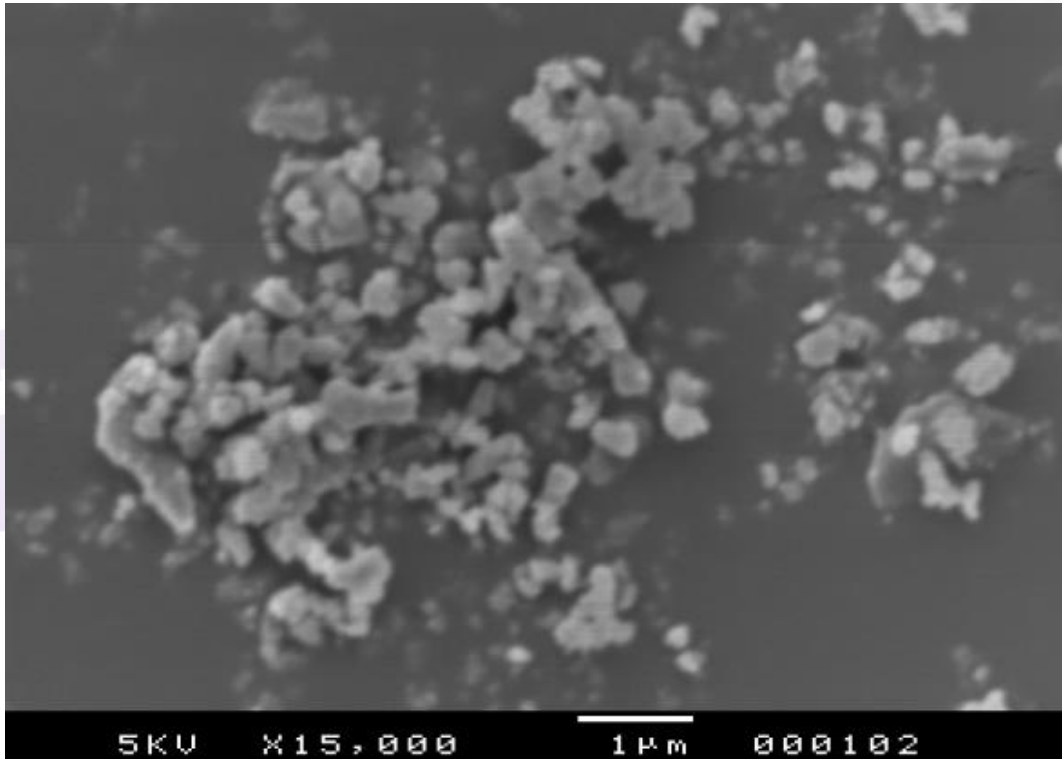
Detail of the centre of a micro -pyramid (25 layers of 50 microns each)



A micro-wheel (5 micron layers)



Photopolymer Rapid Opto-electronic Manufacture of Macro/micro Prototype Products - BRITE-EURAM



Alumina (Al_2O_3) Powder: Average diameter $0.5\mu\text{m}$;
Refractive index 1.7

Monomer: hexane-diol-
diacrylate (HDDA)

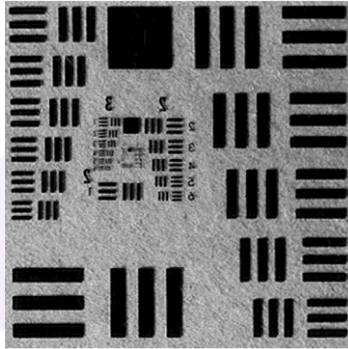
Photoinitiators:

Igracure 651 (DMPA) absorbs
300-390 nm

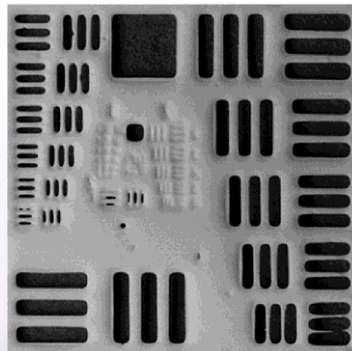
Igracure 819 absorbs up to
450 nm

50 mJ/cm^2 for $100\mu\text{m}$ cure
depths, resolution of $40\mu\text{m}$

Photopolymer Rapid Opto-electronic Manufacture of Macro/micro Prototype Products - BRITE-EURAM

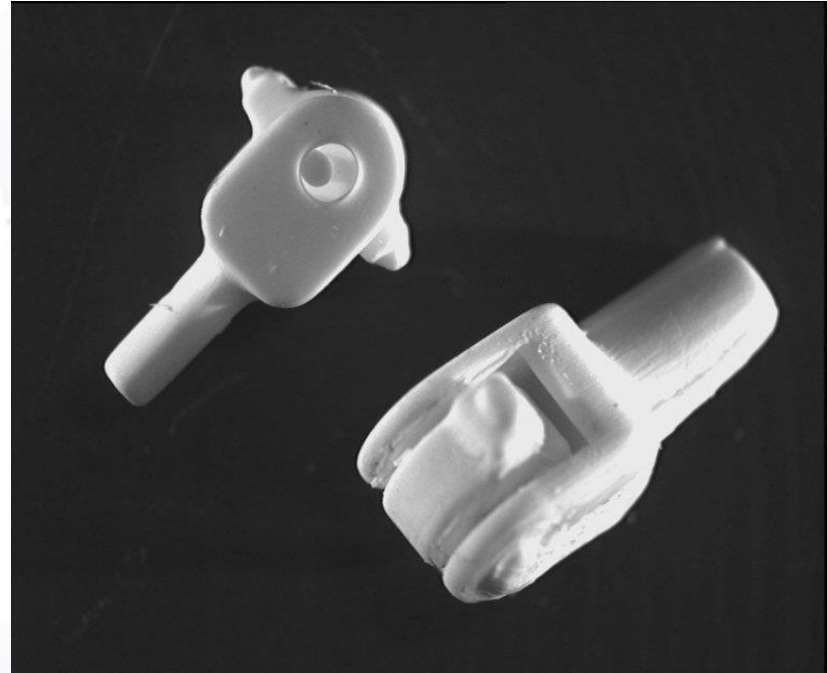


Mask



Cured at 365 nm
with Hg Lamp

8mm x 8mm 120 micron thick polymerised layer,
resolution 50 microns; 80 wt% alumina, 0.5 wt%
DMPA wrt HDDA monomer

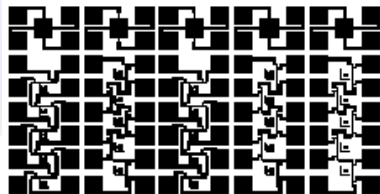
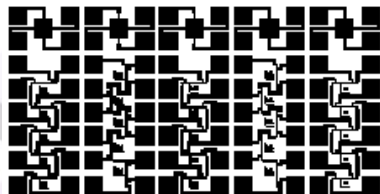


Ceramic parts produced with visible source
and CRL XGA mask

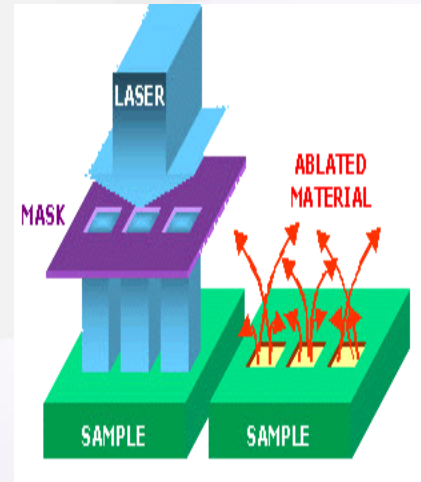
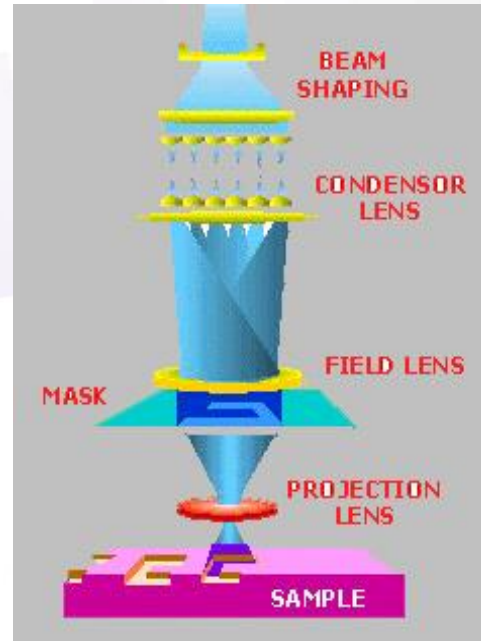
Micromachining - Electronics & Sensors



**Lambda Physik LPX 201i, 125W mean power,
2.5J/pulse, 100 Hz prf, 10 to 50 ns pulse width**



Chrome on Quartz Mask



Micro-fluidic systems



References

- 1) C Chatwin, M Farsari, S Huang, M Heywood, P Birch, R Young, "UV microstereolithography system that uses spatial light modulator technology," *Applied optics* 37 (32), 7514-7522, 1998
- 2) M Farsari, S Huang, RCD Young, MI Heywood, PJB Morrell, CR Chatwin, "Holographic characterization of epoxy resins at 351.1 nm," *Optical Engineering* 37 (10), 2754-2759, 1998
- 3) M Farsari, S Huang, RCD Young, MI Heywood, PJB Morrell, CR Chatwin, "Four-wave mixing studies of UV curable resins for microstereolithography," *Journal of Photochemistry and Photobiology A: Chemistry* 115 (1), 81-87, 1998
- 4) M Farsari, S Huang, P Birch, F Claret-Tournier, R Young, D Budgett, "Microfabrication by use of a spatial light modulator in the ultraviolet: experimental results," *optics letters* 24 (8), 549-550, 1999
- 5) CR Chatwin, M Farsari, S Huang, MI Heywood, RCD Young, PM Birch, "Characterisation of epoxy resins for microstereolithographic rapid prototyping," *The International Journal of Advanced Manufacturing Technology* 15 (4), 281-286, 1999
- 6) GD Ward, IA Watson, DES Stewart-Tull, AC Wardlaw, CR Chatwin, "Inactivation of bacteria and yeasts on agar surfaces with high power Nd: YAG laser light," *Letters in applied microbiology* 23 (3), 136-140, 1996
- 7) M Farsari, S Huang, RCD Young, MI Heywood, CD Bradfield, CR Chatwin, "Holographic cure monitoring of the DuPont Somos TM 7100 stereolithography resin," *Optics and lasers in engineering* 31 (3), 239-246, 1999
- 8) M Farsari, F Claret-Tournier, S Huang, CR Chatwin, DM Budgett, "A novel high-accuracy microstereolithography method employing an adaptive electro-optic mask," *Journal of Materials processing technology* 107 (1), 167-172, 2000
- 9) P Birch, R Young, C Chatwin, M Farsari, D Budgett, J Richardson, "Fully complex optical modulation with an analogue ferroelectric liquid crystal spatial light modulator," *Optics communications* 175 (4), 347-352, 2000
- 10) PM Birch, R Young, D Budgett, C Chatwin, "Two-pixel computer-generated hologram with a zero-twist nematic liquid-crystal spatial light modulator," *Optics letters* 25 (14), 1013-1015, 2000
- 11) P Birch, R Young, M Farsari, C Chatwin, D Budgett, "A comparison of the iterative Fourier transform method and evolutionary algorithms for the design of diffractive optical elements," *Optics and Lasers in engineering* 33 (6), 439-448, 2000
- 12) P Birch, R Young, D Budgett, C Chatwin, "Dynamic complex wave-front modulation with an analog spatial light modulator," *Optics letters* 26 (12), 920-922, 2001

